

Screw dislocations in GaN

Nanosurf[®] - Application Note No. 00164

Gallium nitride features some unique properties [1] such as large band gap, strong interatomic bonds, and high thermal conductivity. Along the last decade, GaN has attracted great interests owing to its potential applications in high power and high frequency electronic devices [2] as well as in blue LED devices [3]. GaN layers are usually grown by Metal Organic Chemical Vapor Deposition and the Molecular Beam Epitaxy methods.



Sapphire is now the most commonly used substrate athough of its highly mismatched lattice and thermal expansion coefficients. As consequence, the obtained GaN layers often contain an large number defects [4], mainly dislocations. The image shows a piece of GaN with steps and screw dislocations (holes). The goal is to count number of dislocations and step distribution.

GaN, different sample preparation conditions. Image size 5x5 um, Z-range 1.5 nm

Sample courtesy: Dr Rachel Oliver, The Cambridge Centre for Gallium Nitride, Department of Materials Science and Metallurgy, University of Cambridge.

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Can be measured with:	Mobile S HR Nanite B HR easyScan 2 AFM HR	Application domain:	Coating Material Science Physics
			New Material